

ABSTRACT

Described is a system designed to warm the transfer chamber used in vacuum equipment in the manufacture of integrated circuits during maintenance. The system detects when the transfer chamber lid is opened and the chamber is exposed to the atmosphere. This activates the heater normally used to bake out the chamber. A temperature sensor is used to keep the temperature below a set point. By warming the chamber, moisture build-up on the inside of the chamber during maintenance is minimized, thereby reducing out gassing and time required to bring the chamber back to its base vacuum pressure when returned to production.

|| FIGURE 1



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